

Automated interference microscope MIA-2

It is **DESIGNED FOR** non-contact measurement of the surface shape of objects in the micro- and nano-ranges of heights, altitude and step parameters of roughness, thickness of thin films, distribution of refractive index, etc.

The microscope **ALLOWS** you to explore reflective objects, consisting of materials that are different in their electrical properties (dielectric, conductor, etc.).

It **CAN BE USED** in biology to study microbiological objects without staining, placed on a mirror surface.



Field of vision, μm	130 × 175
Altitude measurement range, μm	0,0001 ÷ 3,0000
Resolution capacity in	
· plane XY, μm	0,3
· by axe Z, Å	0,8
Refractive index measurement range	1 ÷ 2
Absolute measurement error of the refraction index	$1 \cdot 10^{-3}$
Radiation sources	light emitting diode
Wave length, μm	0,532
Reconstruction algorithm	method of phase steps
Image dimension, pixel	1392 x 1040
Time of measurement and processing, sec	30
Number of processed interference images	9